

Amendments to the Claims:

1. **(Currently amended)** A sputtering device constituted of ~~at least a substrate,~~ a substrate holder for holding ~~said a~~ substrate, at least one target for forming a thin film on ~~said the~~ substrate, and at least one sputtering cathode in which said target is installed, wherein:
 an axis of said target is inclined to an axis of said sputtering cathode, and
 said sputtering cathode is rotated on its axis to make said target swing relative to said substrate holder.
2. **(Original)** A sputtering device according to claim 1, wherein:
 said substrate holder is rotated on its axis.
3. **(Original)** A sputtering device according to claim 2, wherein:
 magnets are arranged behind said target and rotated on its axis.
4. **(Currently amended)** A sputtering device according to claim 3, wherein:
 said sputtering cathode is inclined relative to an axis of ~~the said~~ substrate holder.
5. **(Currently amended)** A sputtering device according to claim 4, wherein:
 a plurality of sputtering cathodes are arranged relative to said substrate holder.
6. **(Currently amended)** A sputtering device according to claim 5, wherein:
 said plurality of said sputtering cathodes can be revolved around the axis of ~~the said~~ substrate holder.
7. **(Currently amended)** A sputtering device according to claim 6, wherein:
 a shutter is arranged between said sputtering cathodes and said substrate holder to open and close said sputtering cathodes selectively.

8. **(Original)** A sputtering device according to claim 7, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
9. **(Original)** A sputtering device according to claim 8, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.
10. **(Original)** A sputtering device according to claim 1, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
11. **(Original)** A sputtering device according to claim 10, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.
12. **(Original)** A sputtering device according to claim 2, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
13. **(Original)** A sputtering device according to claim 12, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.
14. **(Original)** A sputtering device according to claim 3, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
15. **(Original)** A sputtering device according to claim 14, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.

16. **(Original)** A sputtering device according to claim 4, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
17. **(Original)** A sputtering device according to claim 16, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.
18. **(Original)** A sputtering device according to claim 5, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
19. **(Original)** A sputtering device according to claim 18, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.
20. **(Currently amended)** A sputtering device according to claim 6, wherein:
a protection shield is provided around said substrate holder to prevent forming a film
clung around or beside said substrate holder.
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21. **(Original)** A sputtering device according to claim 20, wherein:
said protection shield can be rotated along a circumferential edge of said substrate holder.